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PATENT  
81877.0007

#11  
7604  
5-203

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
TECHNICAL CENTER 2800

In re application of:  
Norikazu MIZUNO, et al.

Serial No: 09/670,917

Filed: September 29, 2000

For: SEMICONDUCTOR DEVICE  
MANUFACTURING METHOD AND  
APPARATUS FOR REMOVING SILICON  
NITRIDE FORMED IN A REACTION  
CONTAINER WITH  $\text{NF}_3$  GAS FLOWING  
INTO THE REACTION CONTAINER (AS  
TWICE AMENDED)

Art Unit: 2822

Examiner: Maria F. Guerrero

I hereby certify that this correspondence  
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April 21, 2003

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Name

*Diane Zynn*

04/21/03

Signature

Date

**PETITION FOR EXTENSION OF TIME**

Box RCE  
Commissioner for Patents  
Washington, D.C. 20231

Dear Sir:

In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the  
Commissioner for a three-month extension of time extending to April 22, 2003, the period  
for response to the Final Office Action dated October 22, 2002. Please charge the fee of  
\$930 for this extension to Deposit Account No. 50-1314. The responsive paper(s) are  
attached.

Please charge any insufficiency or credit any overpayment to Deposit Account  
No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

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02 FC:1253 930.00 CH

Date: April 21, 2003

By:

*Ying Chen*

Registration No. 50,193

Attorney for Applicant(s)

500 South Grand Avenue, Suite 1900  
Los Angeles, California 90071  
Phone: 213-337-6700  
Fax: 213-337-6701